

LAAS - Plateforme de Micro et Nano Technologies

**FIT 2024 : 1er forum scientifique sur l'instrumentation en
physico-chimie à Toulouse : 17 et 18 juin 2024**

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LAAS-CNRS: Key Figures

Made and understand complex systems



CNRS Research Lab: UPR 8001



581 People (~200 C&EC, ~140 ITA, ~240 phd student/postDoc)
115 hosted (Partners, Renatech, ...) **250 intership**
50 PhD defenses/year



Buildings
21 000 m²



Budget
17 M€/year (operational budget)

Funding sources

50% National, 20% Europe, 20% Industry, 5% Region ...



Contracts/collaborative projects

400 active contrats



21 European projects, 4 ERC
13 PEPR, 3 Equipex, 8 Défis-Clef, ...



5 joint Labs with industry

(ROB4FAM-AIRBUS, EPICENTRE-RIBER,
 OPALE-ESSILOR, LICUR-CEA, DYNAMOGRADE-TOWARD)

1 industrial chair (OneStock, INPT, CNRS)

10 CIFRE/year in average

11 Startups created since 2010, 2 ongoing



Multiple international collaborations



Scientific areas – Departments - Applications

COMPUTER SCIENCE

AUTOMATIC
CONTROL

ROBOTICS

MICRO & NANO
SYSTEMS



Trustworthy
computer
systems and
networks
(RISC)



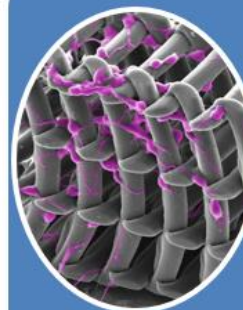
Decision &
Optimisation
(DO)



Robotics
(ROB)



Energy
Management
(GE)



Micro Nano Bio
Technologies
(MNBT)



Microwave and
Photonic
Systems
(HOPES)



Health &
Environment



Smart Industry



Energy



Space



Transportation
& Mobility

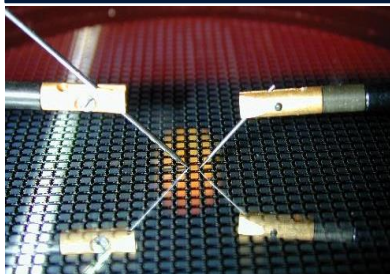
Shared Experimental Platforms

White Room



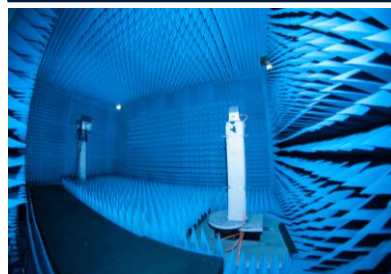
- 40 M€+ equipment, 1600 m²
- 30 technical support personnel,
- 200 users, 160 proj./yr

Electrical Characterisation



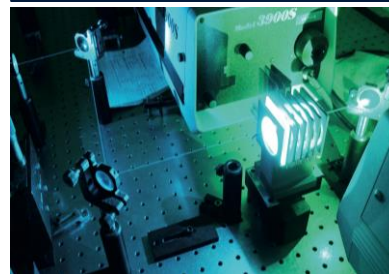
- On wafer measurements: I-V, Z(f), C(V), mapping...
- ESD measurements: TLP, VFTLP, HBM...

Microwave Characterisation



- On wafer characterisation parameters S, spectrum, Noise measurement
- IoT characterization
- 5G Platform

Optics



- Materials characterization
- Passive and active characterization of photonic devices

Biology & chemistry



- Cell cultures
- Fluorescent microscopy
- DNA, RNA, protein quantification

Multifab Fablab



Open platform for 3D, multi-scale, & multi-materials printing

Robotics



- >15 robots
- 3 humanoids, 5 indoor robots, 3 outdoor robots, drones

Space



- Experimentation of embedded systems for space
- nanosatellites

Energy management



- Instrumented experimental building (1700 m²): 100 kWp photovoltaics

Micro and nanofabrication platform



> <https://www.renatech.org/>

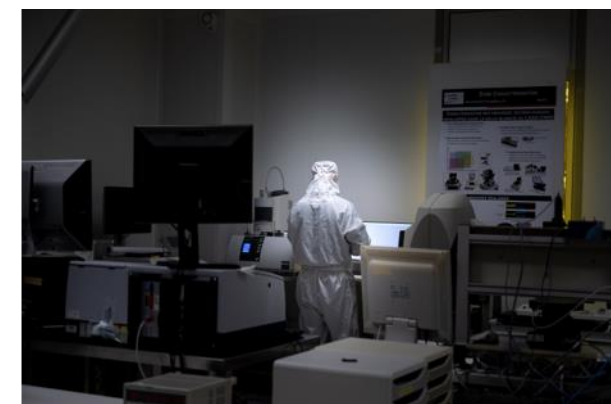
> Since 2003

7300 m²
of clean rooms

140
clean room
engineers
and technicians

130 M€
of EQUIPEMENT

5 FACILITIES

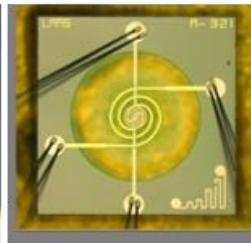
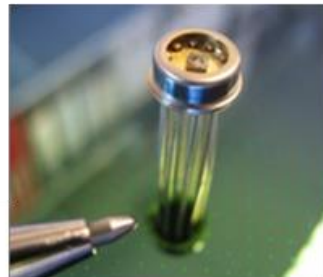


Micro and nanofabrication platform

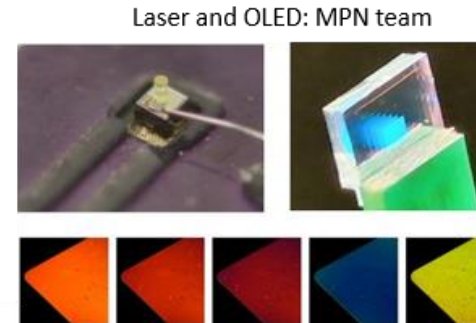


- > **2500 m² (1500 m² clean room)**
 - Clean room expansion (2025-2026) for
 - nanolithography : 200 m²
 - industrial valorization : + 200 m²
- > **30 members (Engineers, High level technicians)**
- > **200+ Users**
- > **160+ Projects / year (average 2014-2023)**
 - 80 internal
 - 80 exogenous
- > **40 M€ + equipment**
 - 220+ tools
 - <https://lims.laas.fr/WebForms/Equipment/EquipmentList.aspx>
- > **Budget ≈ 2,5M€ / an**
 - Operational average: 1,5 M€/an
 - Investments (2014/2020) ≈ 1 M€/an

Micro and nano Systems

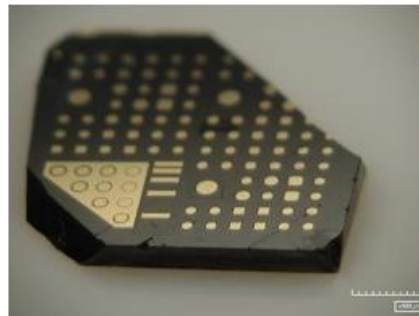


Gas sensor : MICA team



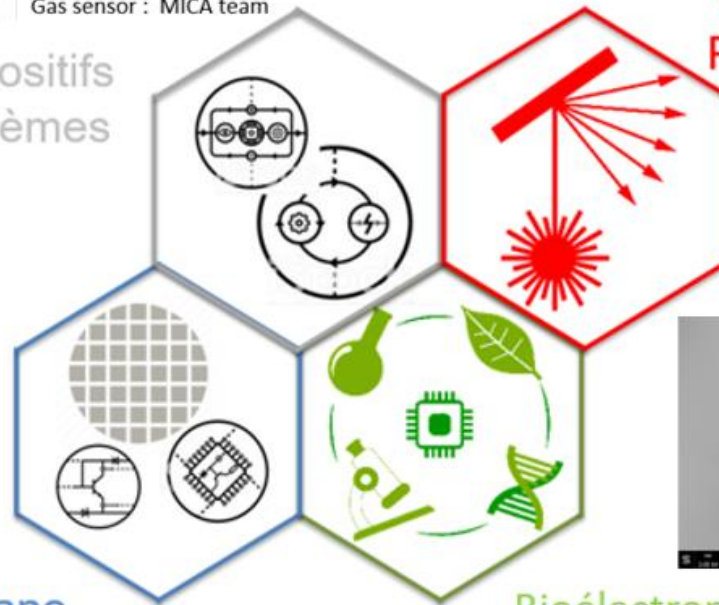
Optique & Photonique

Micro nano dispositifs
micro nano systèmes

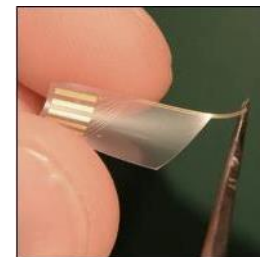
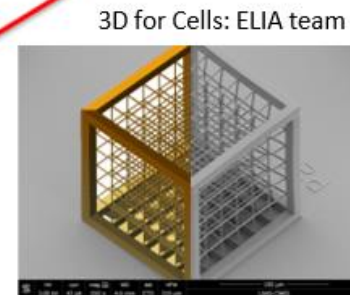


Diodes on diamond: ISGE team

Micro nano
électronique



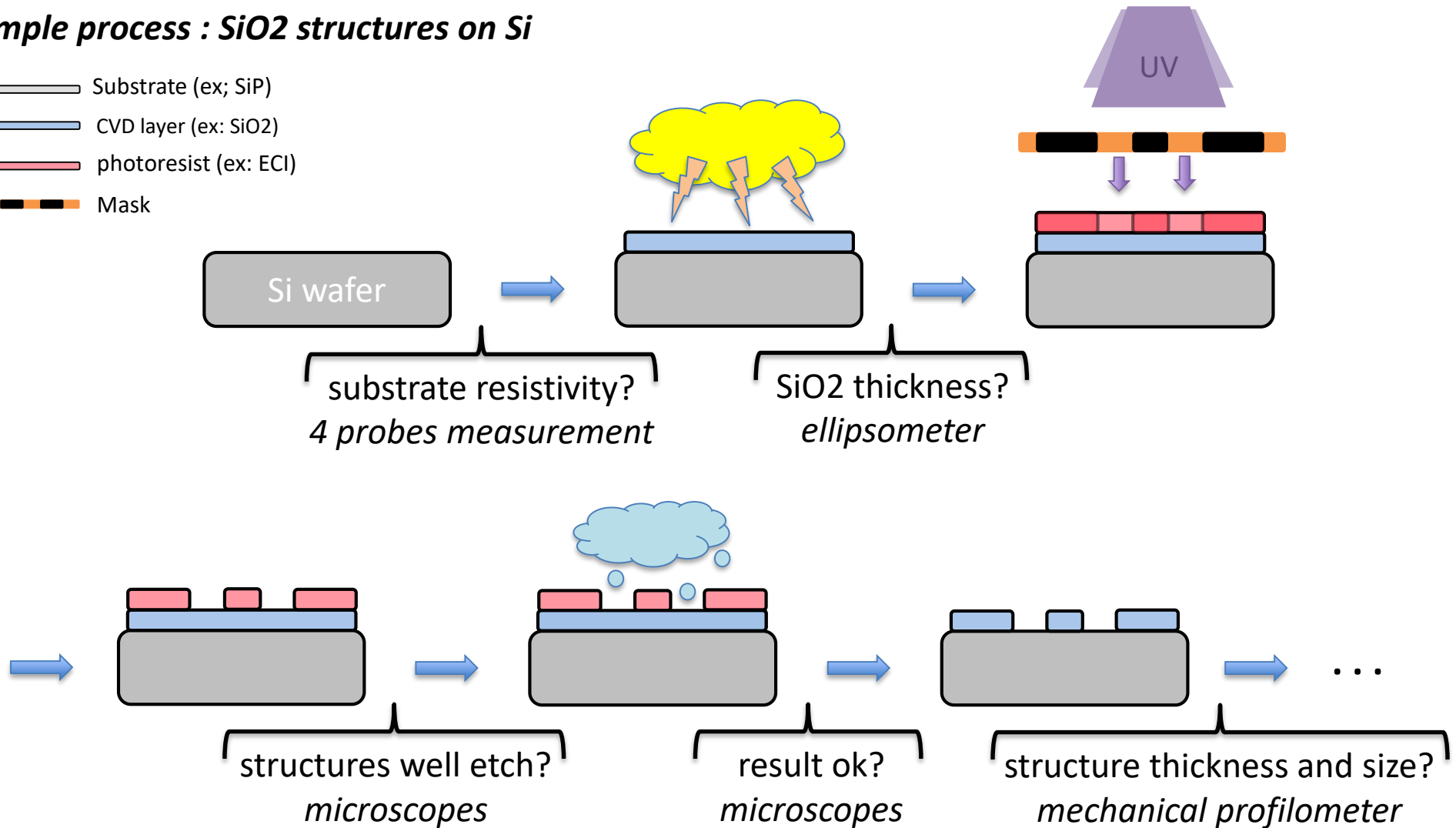
Bioélectronique,
biosystèmes, biophysique



Importance of characterization

Simple process : SiO₂ structures on Si

-  Substrate (ex; SiP)
-  CVD layer (ex: SiO₂)
-  photoresist (ex: ECI)
-  Mask



Our characterization Area (in clean room)



2 people

Dimensional

- 2 optical microscope
- 2 mechanical profilometer
- 2 optical profilometer
- 2 SEM (3 soon)
- 1 dual-beam (SEM+FIB)
- 2 Ellipsometer
- 1 AFM
- *DRX*

Chemical

- FTIR
- X rays analysys EDX & DRX
- *AVS, CVS, Titration & polarographie*

Functional

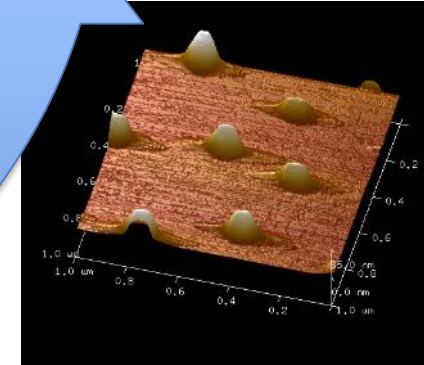
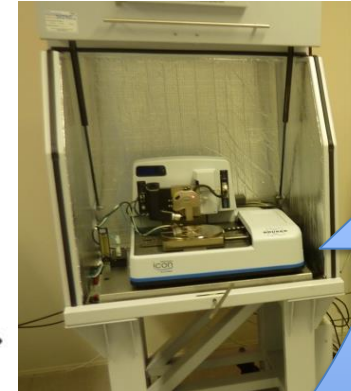
- **Electrical** (probe tester, resistivimeter, AFM)
- **Optical** (Ellipsometer, UV-Vis spectrometer)
- **Surface energy** (contact angle)
- **Thermal** (TGA & DSC)

<https://lims.laas.fr/WebForms/Equipment/EquipmentList.aspx>

Dimensional characterization

Dimensional

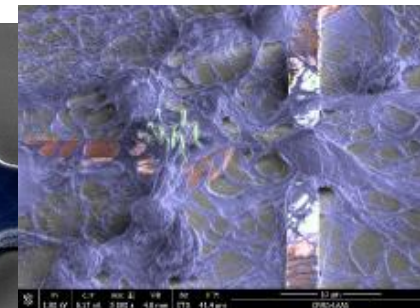
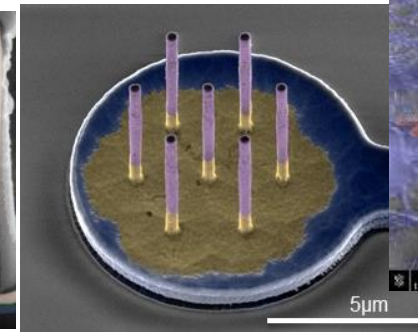
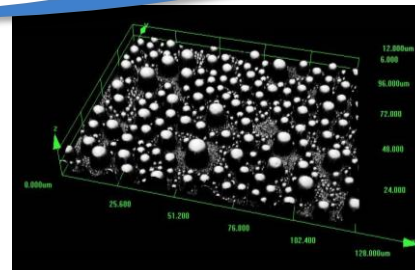
- 2 optical microscope
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GaAs dash

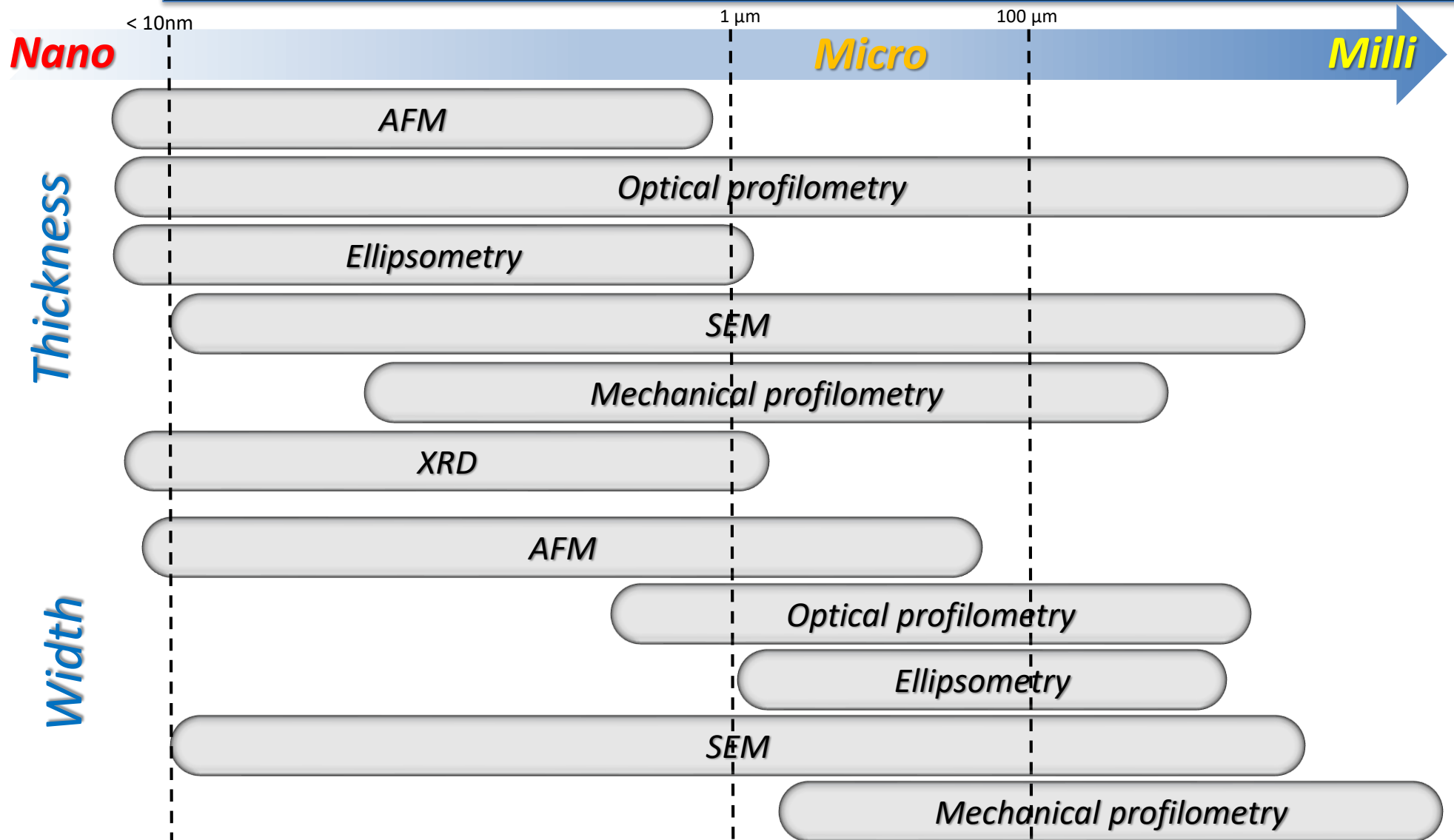


RF system



Nanowire for neuronal activity

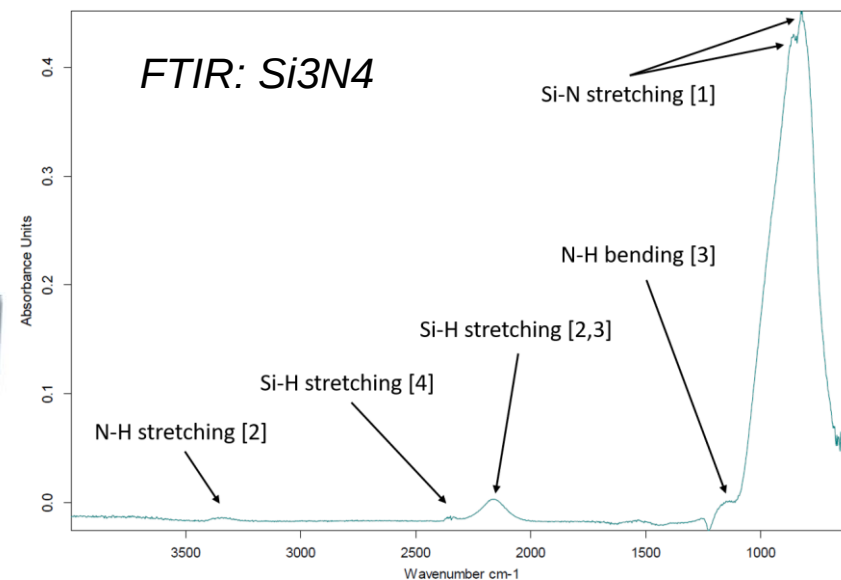
Scale of dimensions



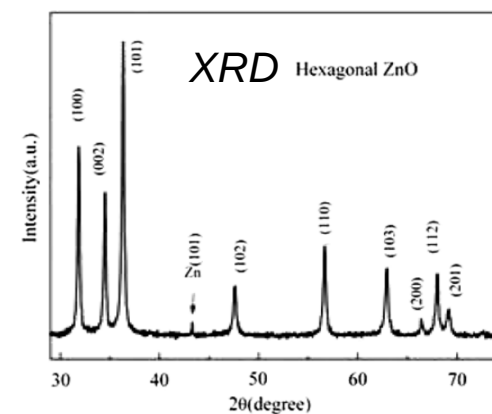
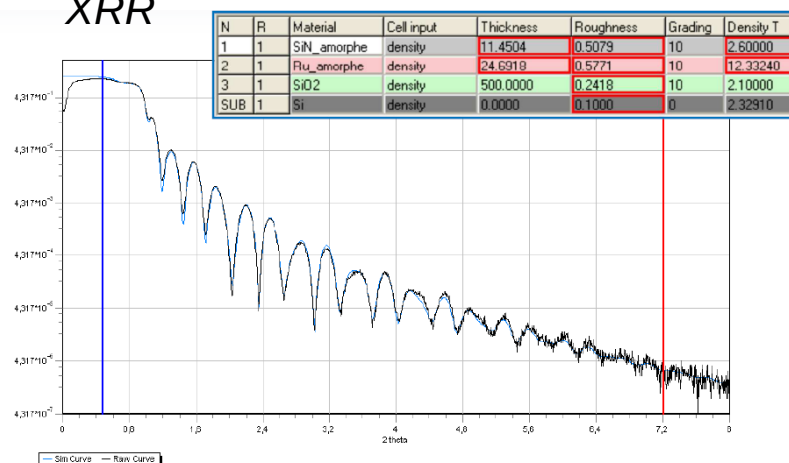
Chemical characterization

Chemical

- FTIR
- X rays analysys EDX & DRX
- AVS, CVS, Titration & polarographie



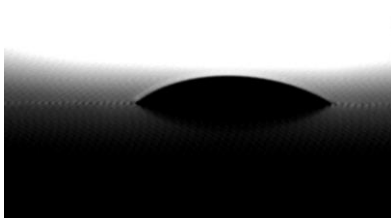
XRR



Functional characterization

Functional

- **Electrical** (probe tester, resistivimeter, AFM)
- **Optical** (Ellipsometer, UV-Vis spectrometer)
- **Surface energy** (contact angle)
- **Thermic** (TGA & DSC)



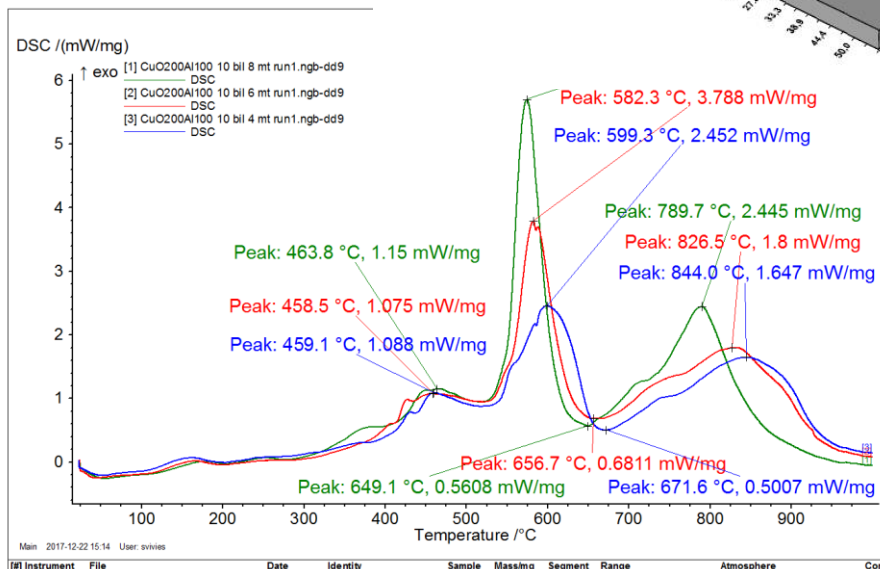
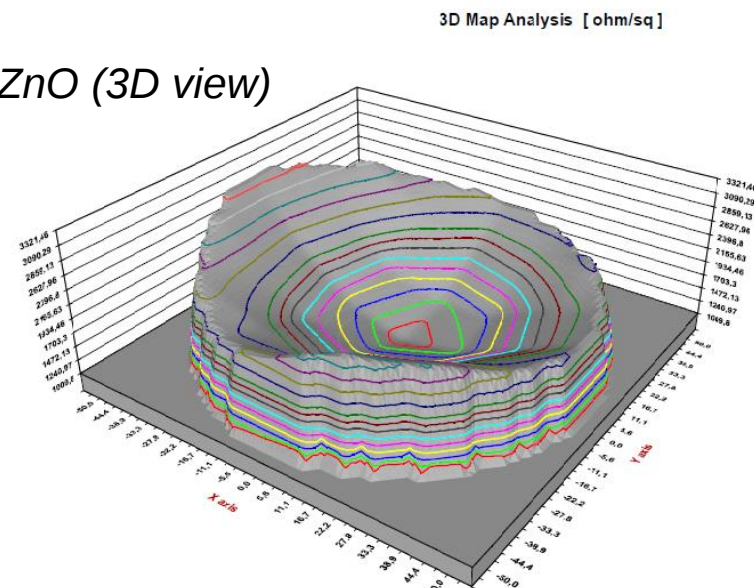
Hydrophilic



Hydrophobic

AlCuO₂ with different vacuum condition for deposit

Mapping of ZnO (3D view)



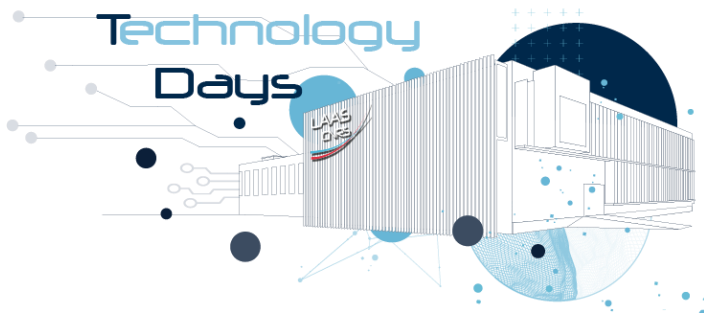
Welcome to LAAS

- Scientific and technical collaboration
- Prototyping
- Service
- Equipment / staff hosting
- Training
- Expertising and consulting



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LAAS
Research and
Technology
Days



9 juillet 2024

<https://www.laas.fr/>

Thank you for your attention

*Understanding the technique to understand the results: **Critic mind** and **reasoned use***